

# 저압 장비 열유동 해석

(주)경원이앤씨

- CFD-ACE+ 소개
- Semiconductor 해석에 필요한 모델 소개
  - Low pressure simulation
  - Convection : Forced vs Natural
  - Effect of Rotating Solids
  - Radiation Effect
  - Chemistry Mixing & reaction
  - Plasma

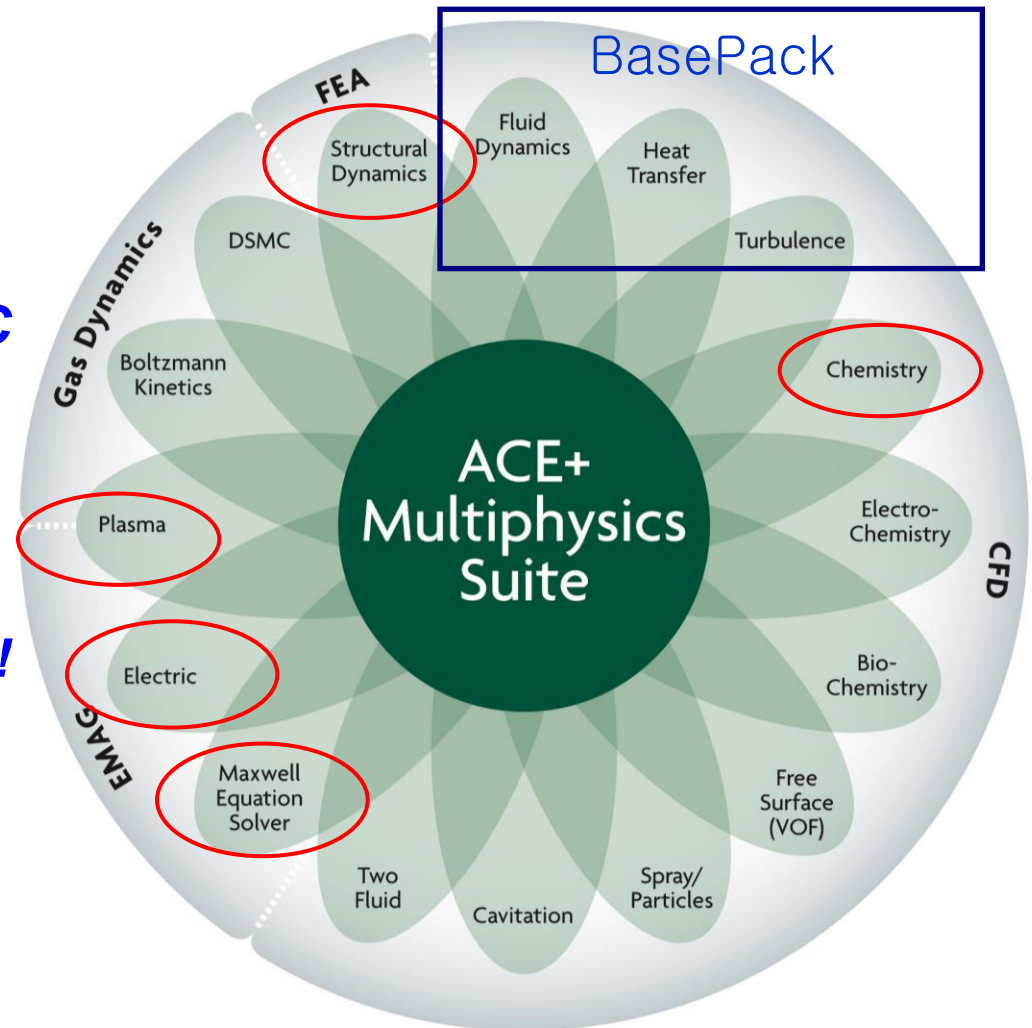
## Advanced CFD and Multiphysics Software

Understanding, Implementation and  
Analysis of Multiphysics simulations :

*Excellent Engineers in KWEnC*

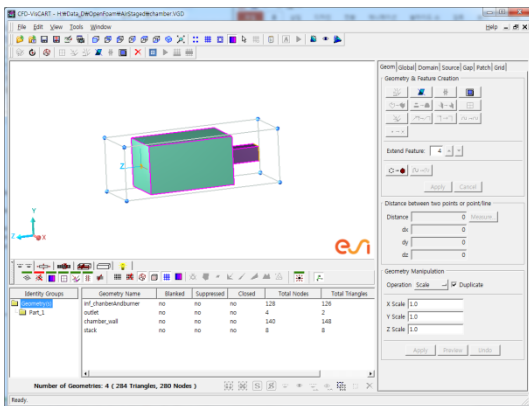
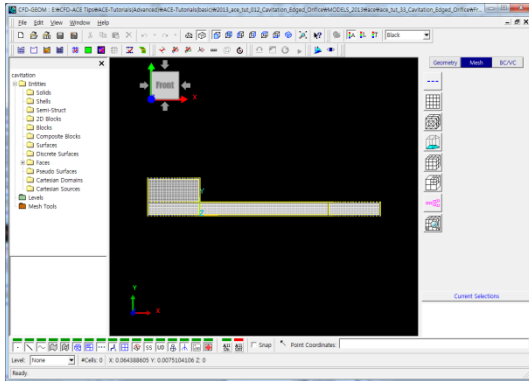
Customers in various industry :

*Has many Industrial Partners !!*

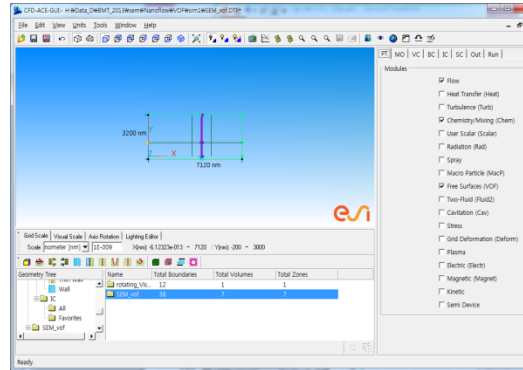


# CFD-ACE+ Product Overview

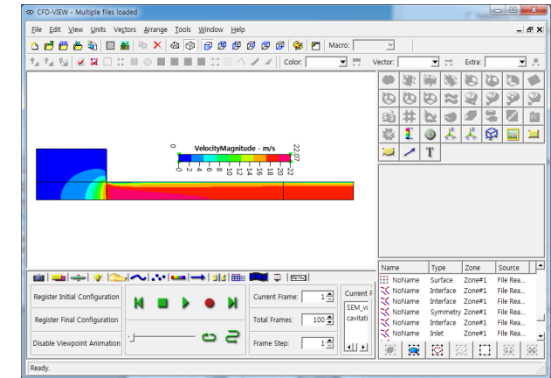
**CFD-GEOM (\*.GGD)**  
**CFD-VisCART(\*.VGD)**



**CFD-ACE-GUI (\*.DTF)**



**CFD-VIEW**



Computational Grid and  
BC / VC Locations

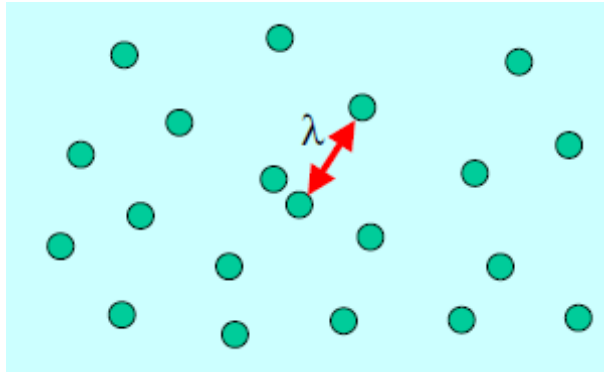
Input Files

Graphical Results

**Batch Solver**  
**CFD-ACE-  
SOLVER**

Text Results

- Implications of Mean Free Path

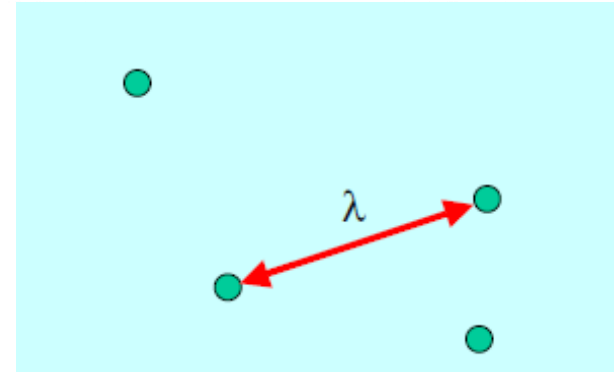


$$p = p_0$$

High collision probability with each other  
Low collision probability with boundary

*Diffusive Transport*

*Equilibrium*



$$p = p_0/5$$

Low collision probability with each other  
High collision probability with boundary

*Ballistic Transport*

*Non-Equilibrium*

- **Applicability of N-S equation**

- $Kn$  = Mean Free Path / Characteristic length =  $\lambda/L$

$Kn < 0.01$  : Continuum

NS equation with conventional no-slip condition

$0.01 < Kn < 0.1$  : Slip Flow Regime

NS with slip-velocity BC

$0.1 < Kn < 3$  : Transitional Regime

Continuum assumption breaks down

$3 < Kn$  : Continuum assumption approach breaks down completely

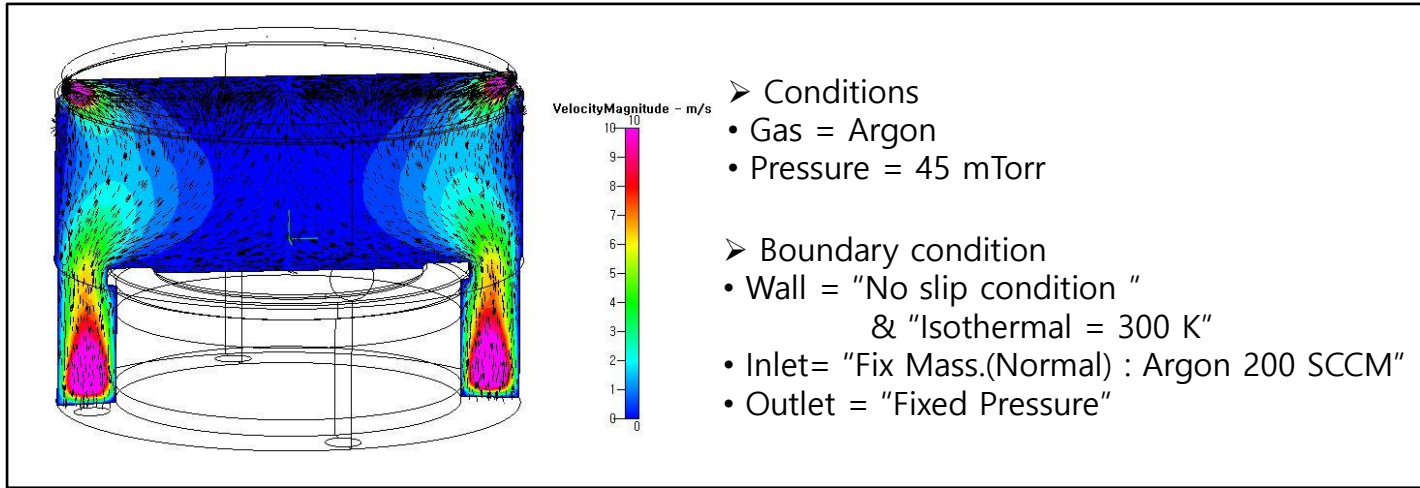
Free Molecular Regime

**CFD-ACE+  
적용 가능**

Discontinuum 영역

※ CFD-ACE+의 진공 해석 가능 압력은 1mTorr 이상 영역에서 적용가능

- Example(Low pressure reactor)



Gas	$\sigma_c(m)$
Air	$3.66 \times 10^{-10}$
Ar	$3.58 \times 10^{-10}$
CO <sub>2</sub>	$4.53 \times 10^{-10}$
H <sub>2</sub>	$2.71 \times 10^{-10}$
He	$2.15 \times 10^{-10}$
Kr	$4.08 \times 10^{-10}$
N <sub>2</sub>	$3.70 \times 10^{-10}$
NH <sub>3</sub>	$4.32 \times 10^{-10}$
Ne	$2.54 \times 10^{-10}$
O <sub>2</sub>	$3.55 \times 10^{-10}$
Xe	$4.78 \times 10^{-10}$

From CRC handbook

$$\text{Mean free path : } \lambda = \frac{RT}{\sqrt{2}\pi\sigma^2 P N_{av}} = \frac{kT}{\sqrt{2}\pi\sigma^2 P}$$

$\sigma$ : collision diameter of molecule

$N_{av}$ : avogadro's number

$P$  : local pressure

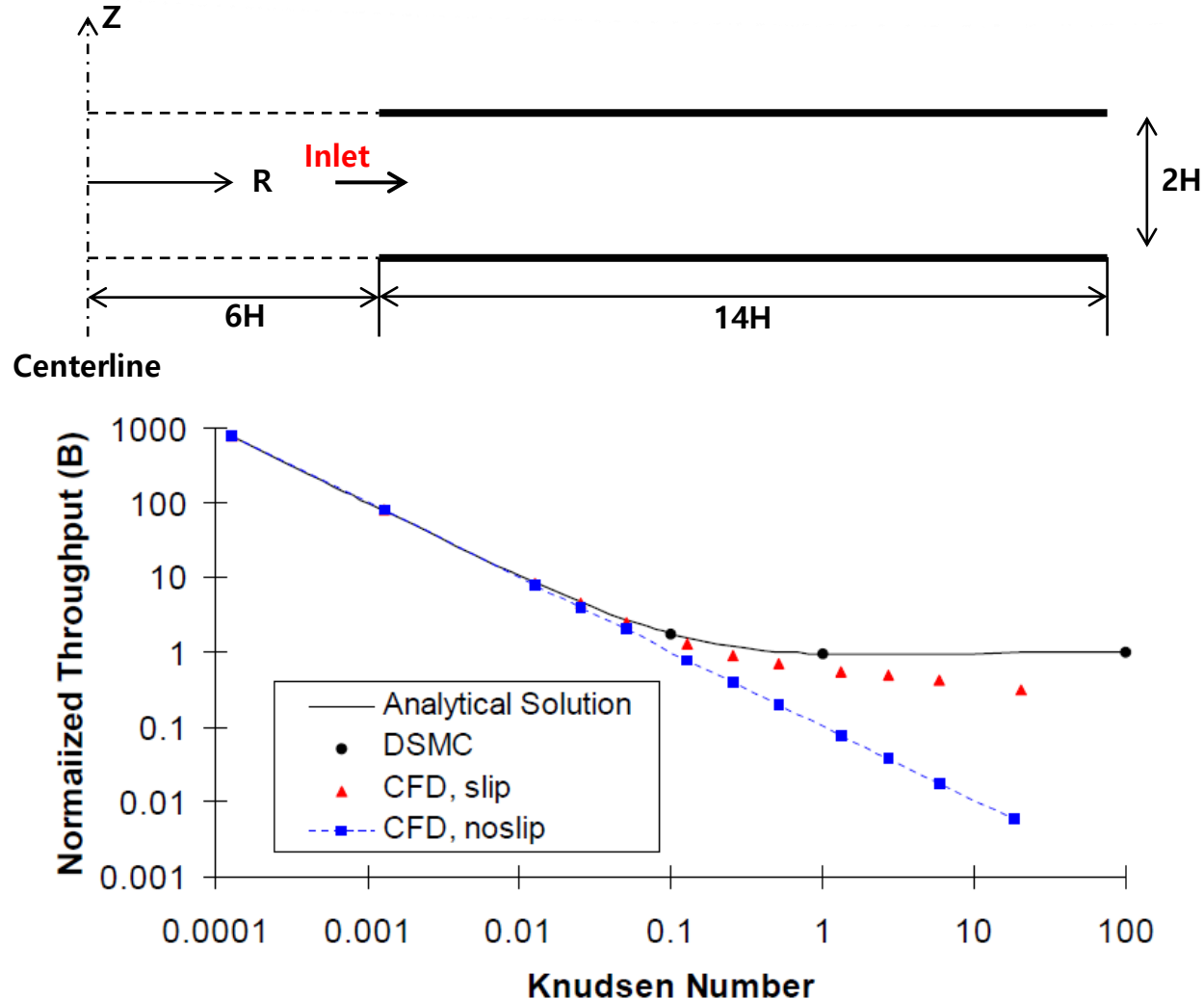
$k$  : Boltzmann constant  $(1.380622 \pm 0.00043) \times 10^{-23}$  J/K

258mm 장치 직경, 진공상태에서(충돌직경 약  $3.58 \times 10^{-10}m$ )의

$$\lambda = \frac{1.38 \times 10^{-23} \times 298}{\sqrt{2} \times 3.14 \times (3.58 \times 10^{-10})^2 \times 6} = 1.152 \times 10^{-3} m$$

$$Kn = \frac{\lambda}{L} = \frac{1.152 \times 10^{-3} m}{0.258 m} = 4.465 \times 10^{-3} \longrightarrow \text{Continuum regime}$$

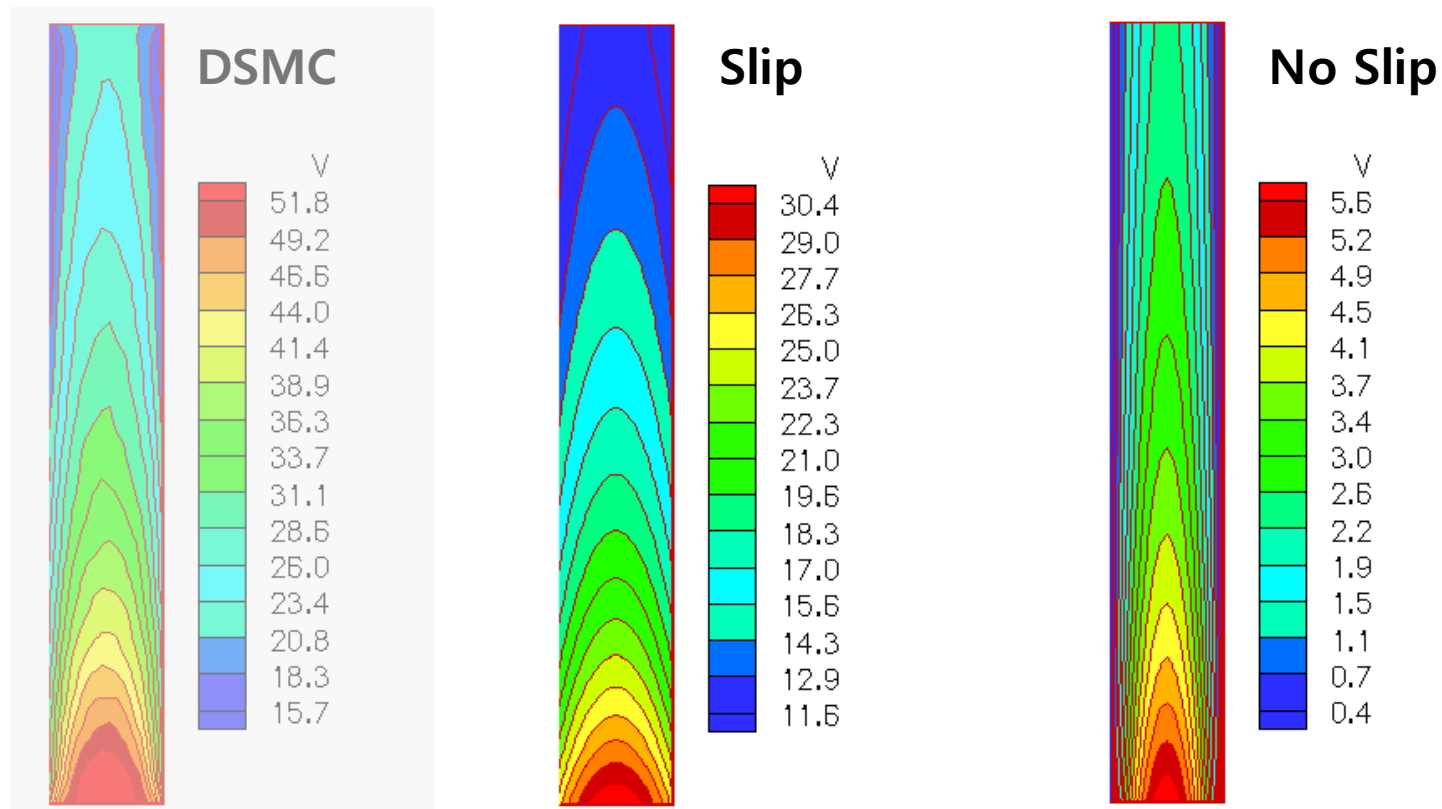
- Validation Study (Performed by Novellus)





- Validation Study (Performed by Novellus)

## Velocity contours for $Kn = 1.0$



현재 CFD-ACE+는 Slip 영역까지 해석 가능

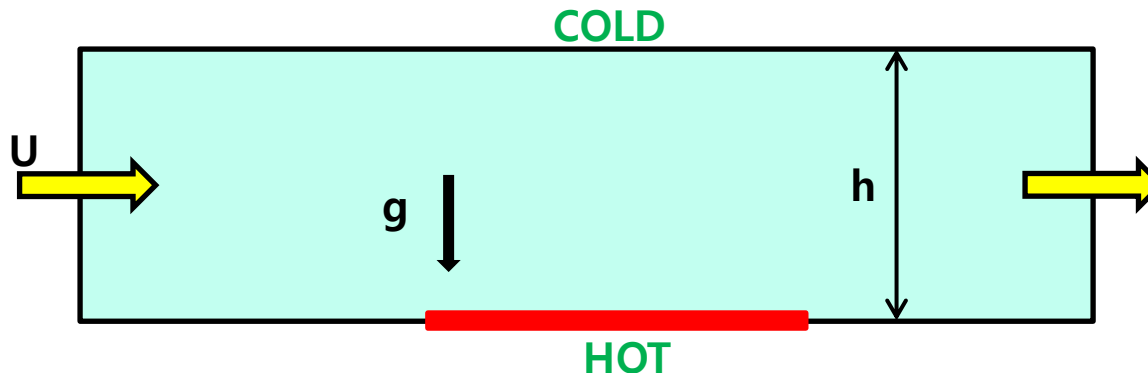
- **Richardson Number**

- For a given reactor geometry, the Richardson number indicates if natural convection is going to be influential or not !!!
- Non-dimensional Numbers

$$Ri = \frac{\text{Buoyancy Force}}{\text{Inertia Force}} = \frac{Gr}{Re^2}$$

$$Re = \frac{\text{Inertia Force}}{\text{Viscous Force}} = \frac{\rho U D_h}{\mu}$$

$$Gr = \frac{\text{Buoyancy Force}}{\text{Viscous Force}} = \frac{g \beta \Delta T h^3 \rho^2}{\mu^2}$$



$h = 10 \text{ cm}$ ,  $U = 0.1 \text{ m/s}$ ,  $g = 9.8 \text{ m/s}^2$ ,  $m = 10^{-5} \text{ kg/m/s}$ , Mol. Wt. =  $29 \text{ kg/kmol}$

- Baseline Case

$$Re = \frac{\rho U D_h}{\mu}; \quad \rho = \frac{pM}{RT}; \quad D_h = 2h$$

$$p = 1.1325E+5, \quad M = 29, \quad R = 8314, \quad T = 300, \quad \mu = 10^{-5}, \quad U = 0.1, \quad h = 0.1$$

$$D_h = 2h = 0.2, \quad \rho = 1.178$$

$$Re = 1178$$

$$Gr = \frac{g \beta \Delta T h^3 \rho^2}{\mu^2}; \quad \beta \approx \frac{1}{(T_H + T_C)/2}; \quad \Delta T = T_H - T_C$$

$$T_H = 310, \quad T_C = 300$$

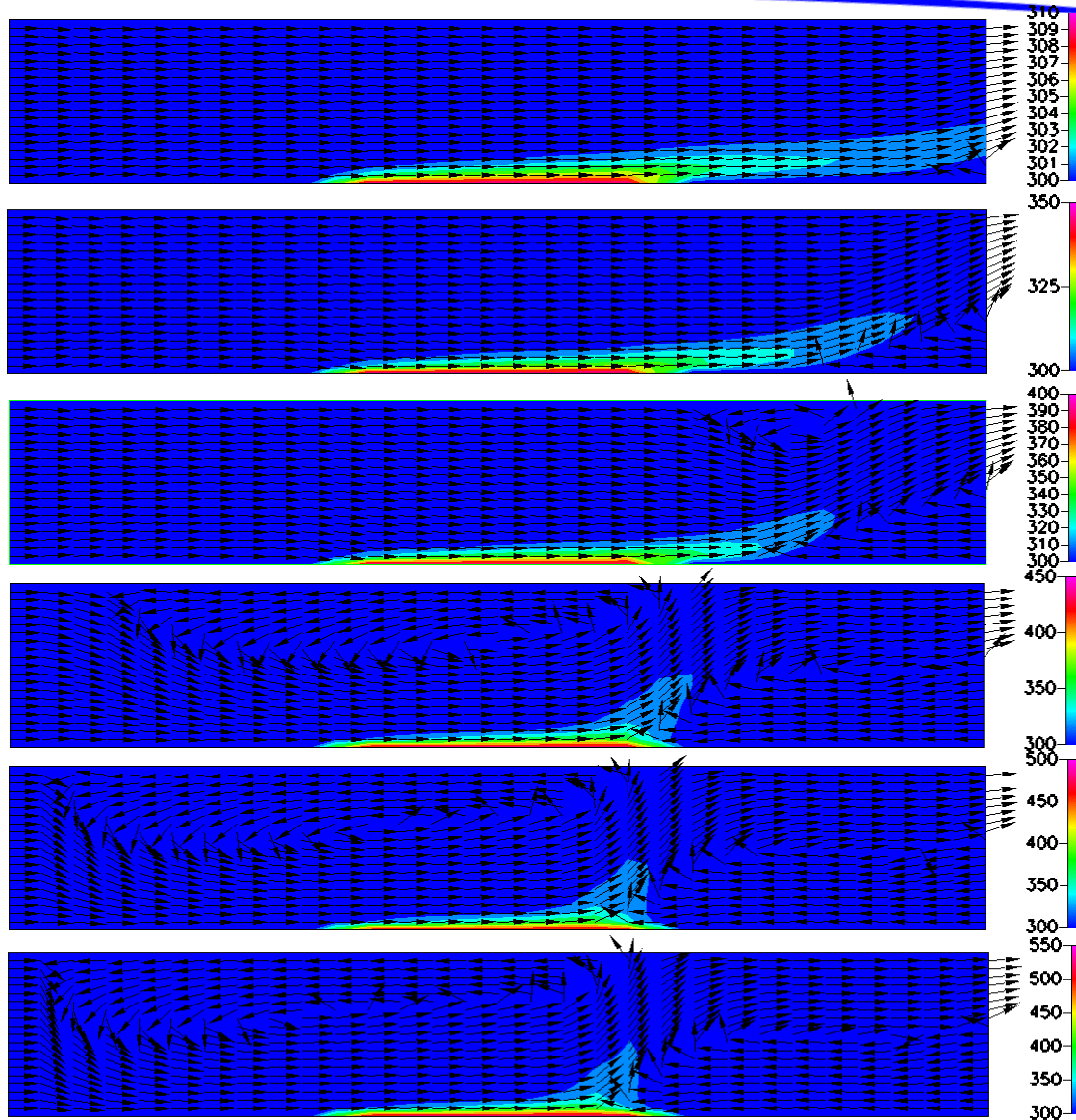
$$\Rightarrow \Delta T = 10, \quad Gr = 446337$$



$$Ri = \frac{Gr}{Re^2} = 3.2$$

$T_H$	$\Delta T$	$Ri = Gr/Re^2$
310	10	3.2
350	50	15.1
400	100	28
450	150	39.2
500	200	49.1
550	250	57.7

# Convection : Forced vs Natural



**Ri = 3**

**Ri = 15**

**Ri = 28**

**Ri = 39**

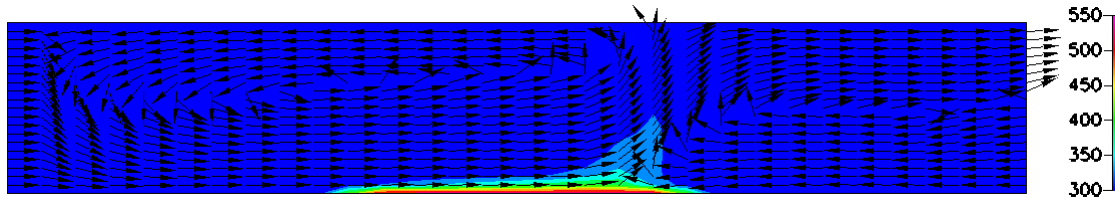
**Ri = 49**

**Ri = 57**

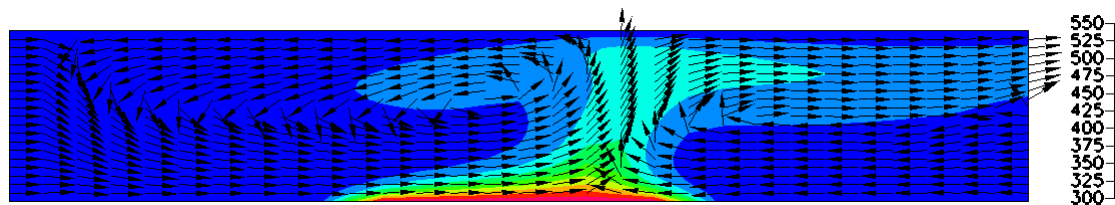
**Conclusion:** If **Ri** > 10, Natural Convection will be important

# Convection : Forced vs Natural

- Effect of Pressure

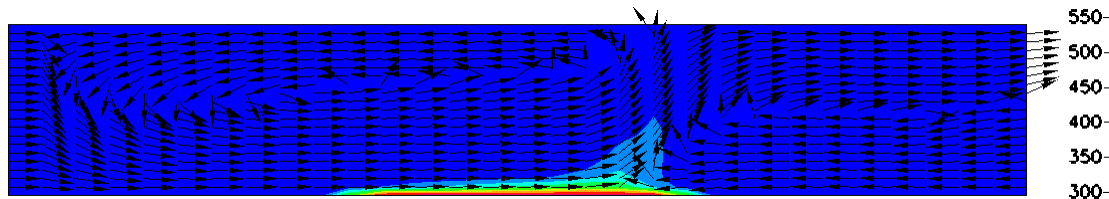


1bar  
 $Ri = 57$



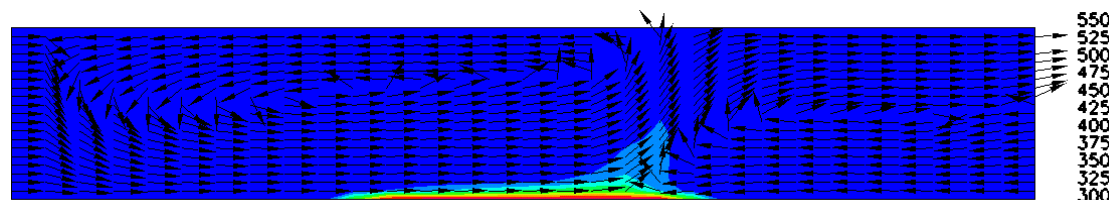
0.1bar  
 $Ri = 57$

- Significance of non-dimensional parameters



$Ri = 57$   $Pr = 0.5$   $Re = 1178$

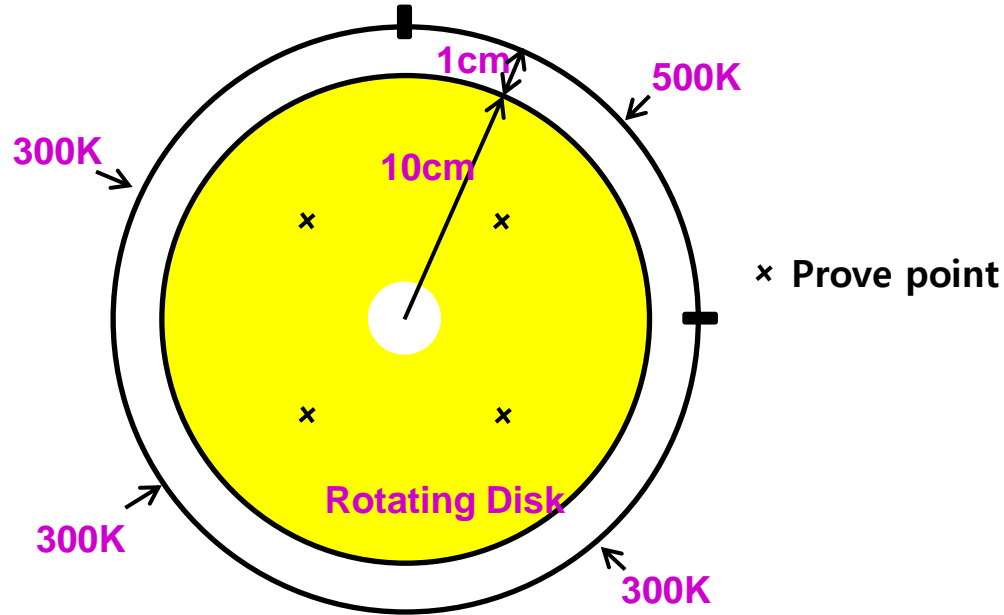
$p = 1$   
 $m = 10^{-5}$   
 $k = 0.0236$



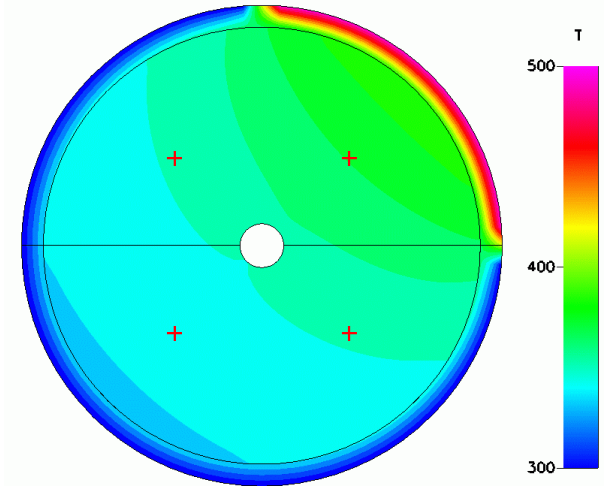
$p = 0.1$   
 $m = 10^{-6}$   
 $k = 0.00236$

# Effect of Rotating

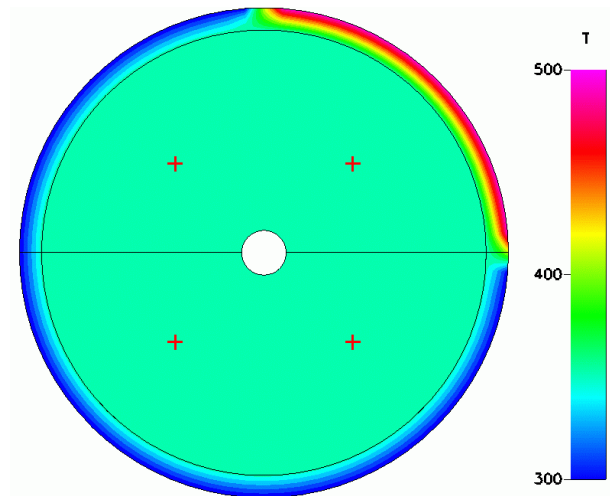
- Validation Study : rotating solids



No Rotation



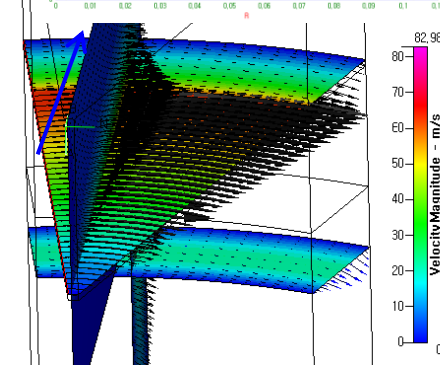
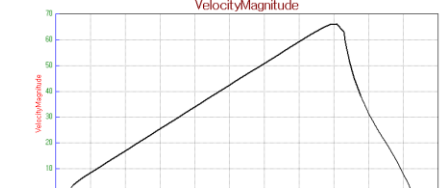
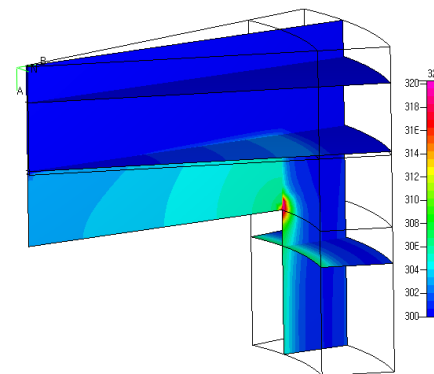
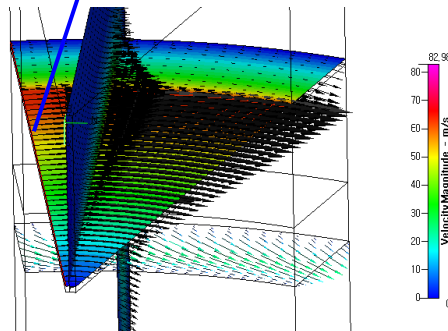
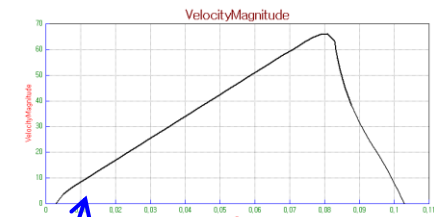
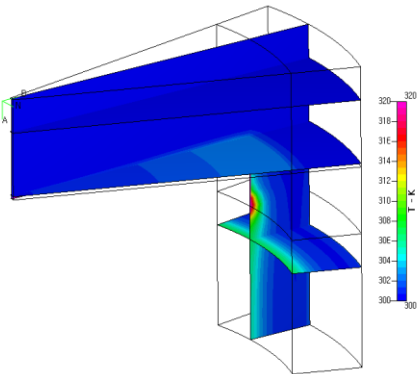
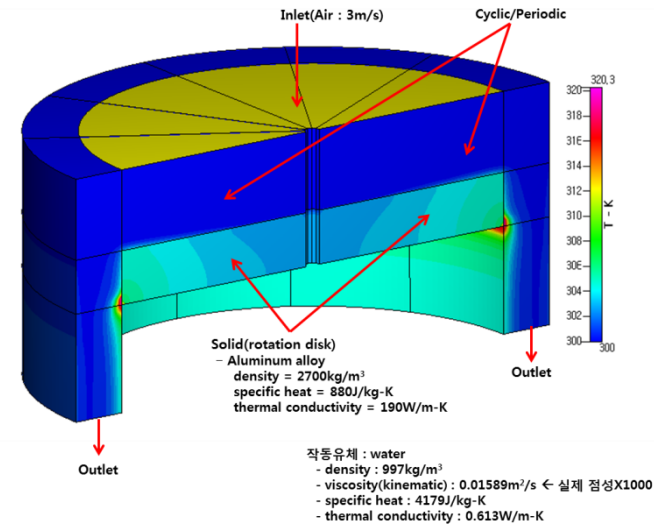
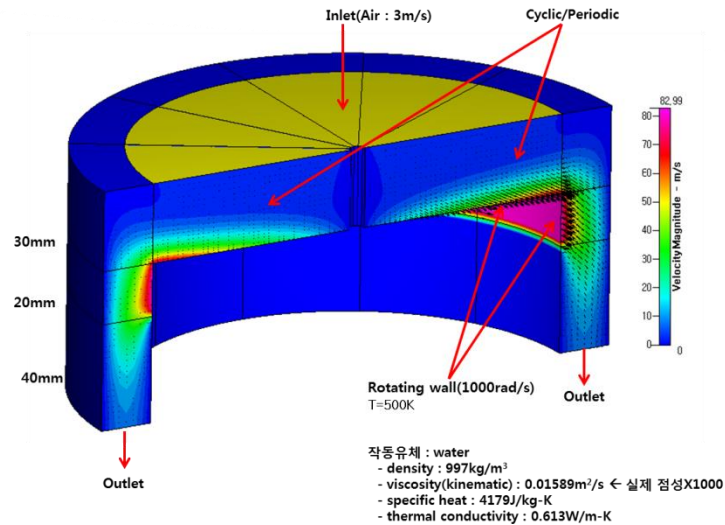
Rotation, 1RPM



- CFD-ACE+에서 적용 가능한 회전체
  - Rotating wall : wall boundary에 rotating 경계조건 적용
  - Solid moving : Conjugate해석과 rotating 해석을 동시에 진행 할 경우 적용
  - MRF : 회전체 정상상태 해석 → Fan, blade 해석에 적합
  - Arbitrary interface : 회전체 비정상상태 해석

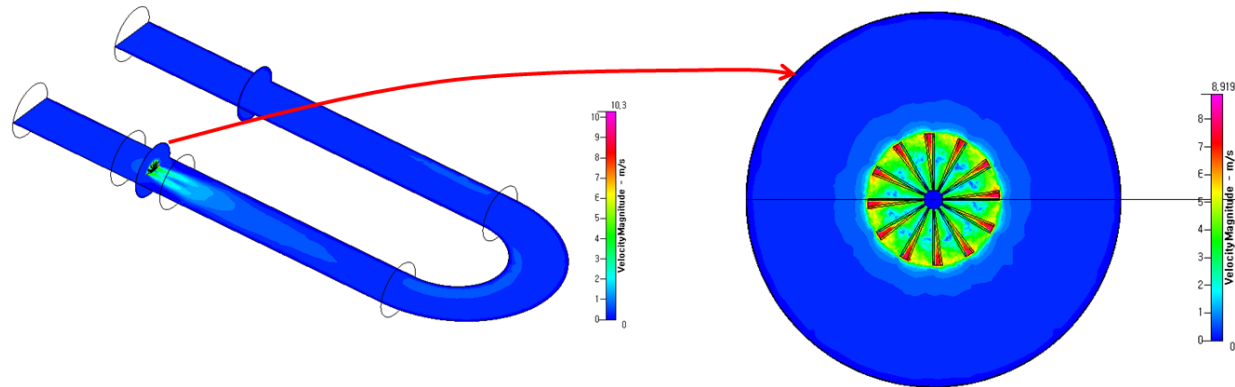
## Rotating wall

## Moving solid

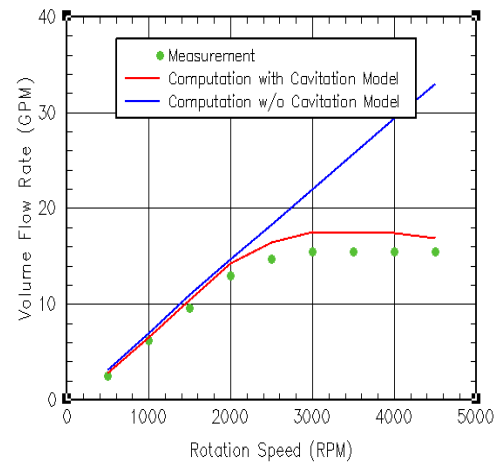
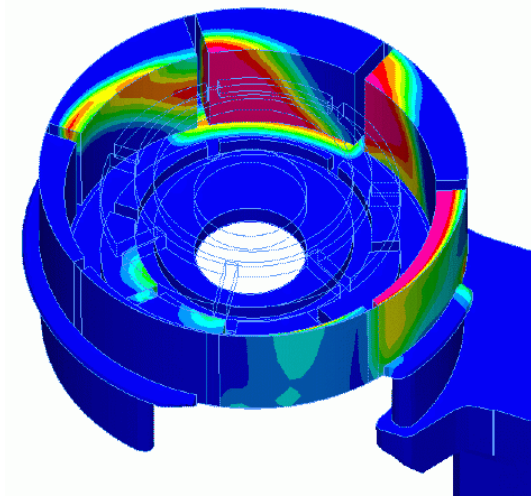




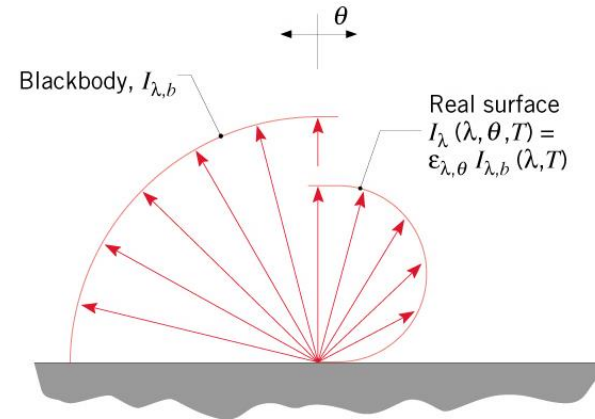
- MRF(Multiple Reference Frame) : 정상상태 해석



- Arbitrary interface : 비정상상태 해석

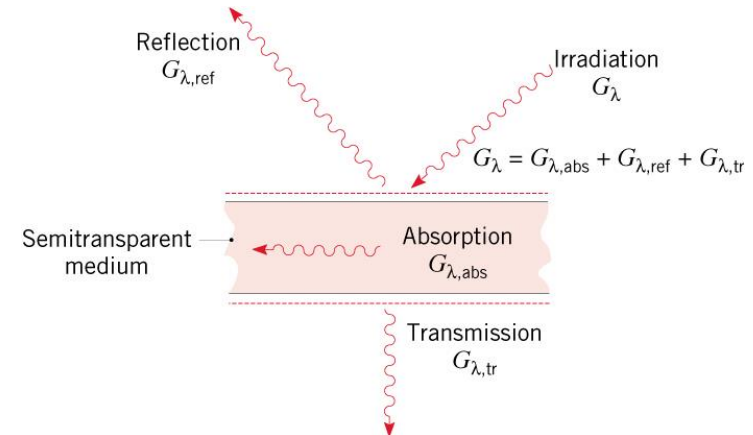


- Surface Emissivity
  - 물질의 고유 특성 Hand book 참조



- Response to Surface Irradiation: Absorption, Reflection and Transmission

- **Reflection** from the medium ( $G_{\lambda,ref}$ ).
- **Absorption** within the medium ( $G_{\lambda,abs}$ ).
- **Transmission** through the medium ( $G_{\lambda,tr}$ ).



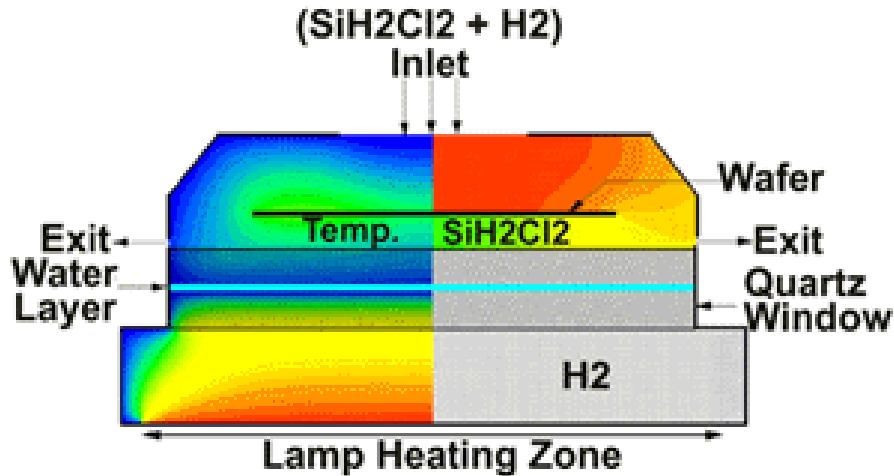
Radiation balance  $\longrightarrow$

$$G_{\lambda} = G_{\lambda,ref} + G_{\lambda,abs} + G_{\lambda,tr}$$

- In contrast to the foregoing **volumetric effects**, the response of an **opaque material** to irradiation is governed by **surface phenomena** and  $G_{\lambda,tr} = 0$ .

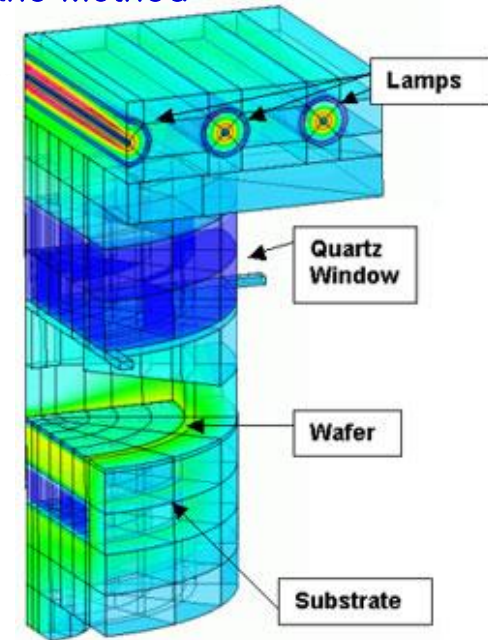
$$G_{\lambda} = G_{\lambda,ref} + G_{\lambda,abs}$$

## Discrete Ordinate Method (DOM)



*CFD-ACE+ Simulation of SEMATECH Benchmark Case with Radiative heating of a wafer via a quartz window with water cooling*

## Monte Carlo Method



*CFD-ACE+ : Simulation of an RTP Reactor using the Monte Carlo Radiation model*

Radiation model은 DOM, Monte Carlo Moethod, STS(surface to surface), P1 모델 등이 있으며 일반적으로 DOM model을 주로 사용함  
 물성 : 기본물성인 density, specific heat, thermal conductivity 이외에 Absorption coefficient, Emissivity등의 물성이 요구 됨.

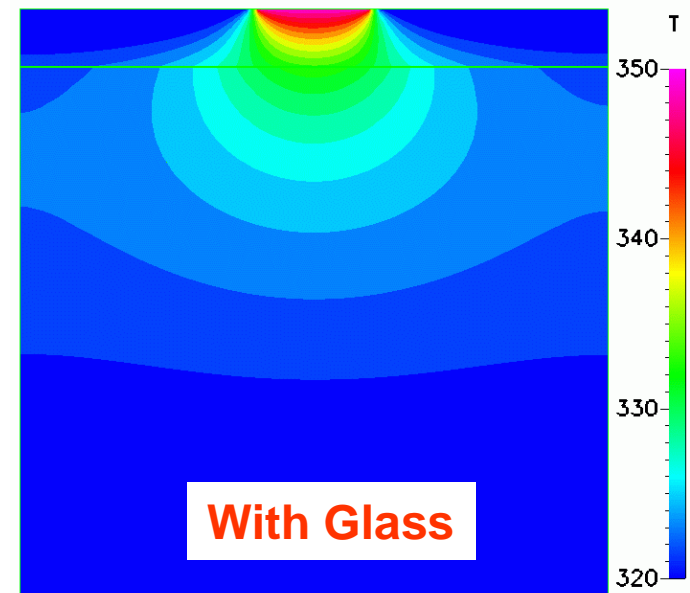
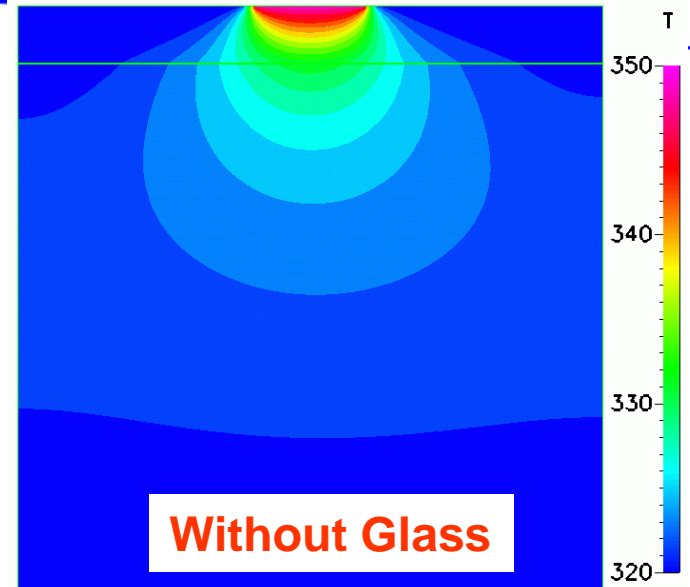
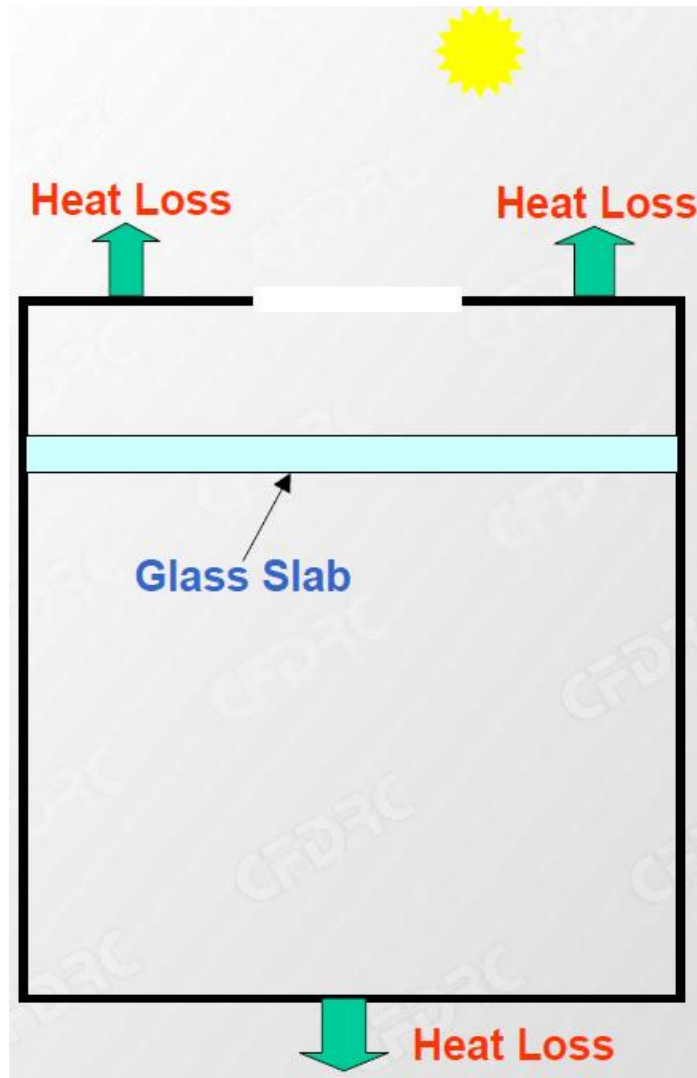
- Effect of Specular Reflection (vs Diffuse)



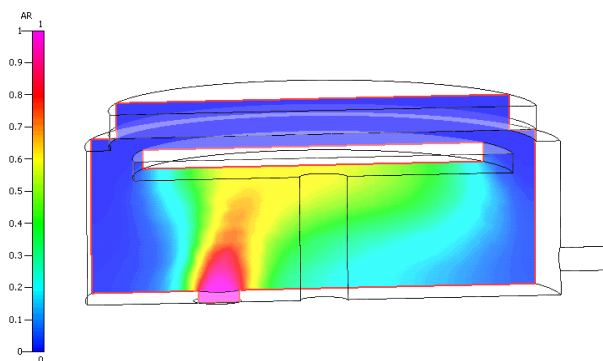
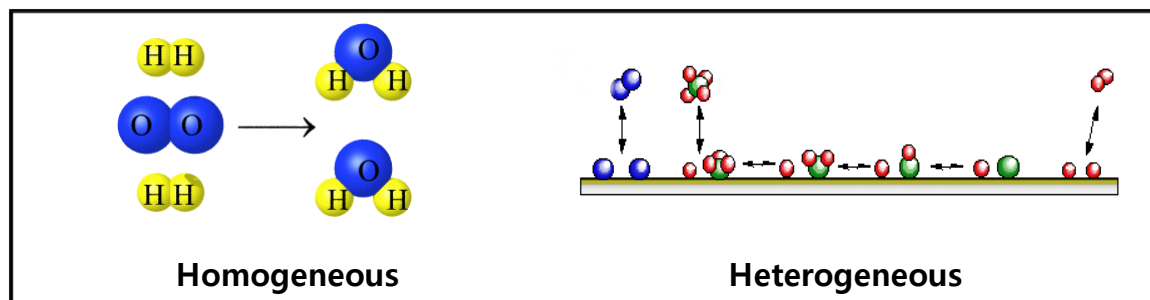
No Radiation: 300.03 K  
DOM, Diffuse: 993.5 K  
MC, Diffuse: 1115.5 K  
MC, partial specular (0.5): 1127.2 K  
MC, specular: 1259.9 K



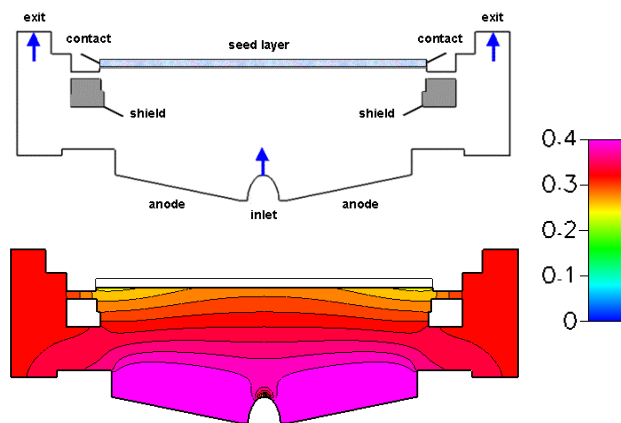
- Non-Gray Effects



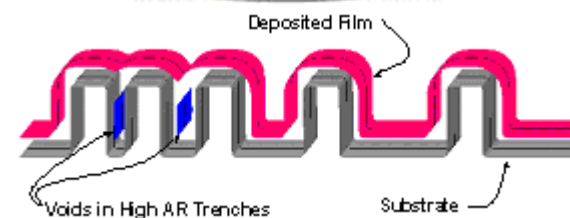
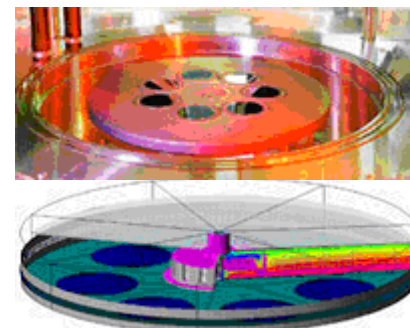
- 단순 혼합 or 화학 반응
  - Mixing
  - Gas phase reaction(homogeneous)
  - Surface reaction(heterogeneous)



CVD chamber – chemistry mixing



Electroplating



반도체 제조 공정 해석

- Species Continuity (or Transport) Equation

$$\frac{\partial \rho Y_i}{\partial t} + \nabla \cdot \rho U Y_i = \nabla \cdot J_i + \dot{\omega}_i$$

$\dot{\omega}_i$  is the rate of production of the i-th species  
due to chemical reaction in the bulk

$J_i$  is the diffusion flux of the i-th species

$$J_i = J_i^C + J_i^T + J_i^P$$

$$J_i^C = \rho D_i \nabla Y_i$$

Fick's Law

$$J_i^T = \rho D_i^T \frac{\nabla T}{T}$$

Soret diffusion

$$J_i^P = \rho D_i^P \frac{\nabla P}{P}$$

Pressure diffusion, usually neglected



- Species Diffusion Coefficient
  - The rate of diffusion of each specie depends on the background species
  - The overall diffusion coefficient of a specie in a given mixture is some combination of the diffusion rates of that specie in each specie of the mixture
- Diffusion Coefficient Calculations
  - Method 1 : Schmidt Number
  - Method 2 : Multi-Component Diffusion 사용

## 1Torr 초과

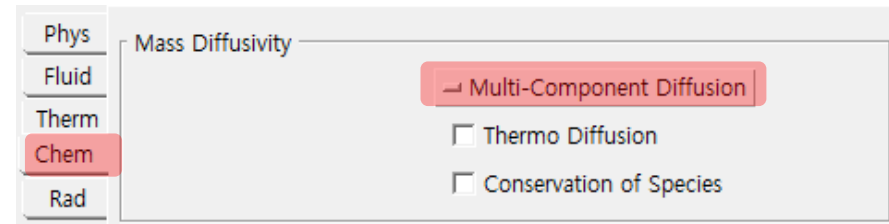
Schmidt Number 사용

$$Sc = \frac{\text{Momentum Diffusivity}}{\text{Mass Diffusivity}} = \frac{\nu}{D}$$

$$\Rightarrow D = \frac{\nu}{Sc}$$

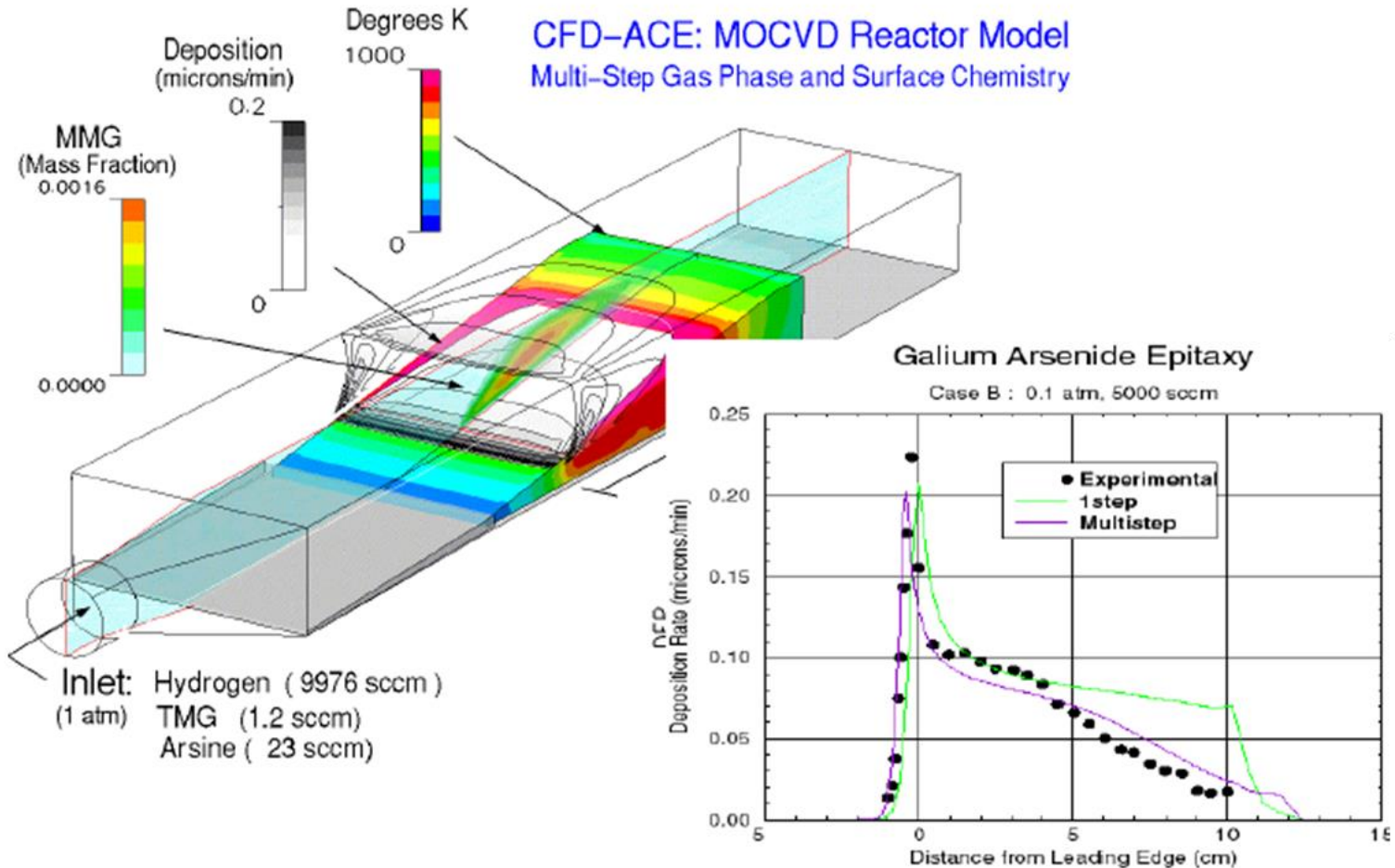
## 1Torr 이하

Multi-Component Diffusion 사용

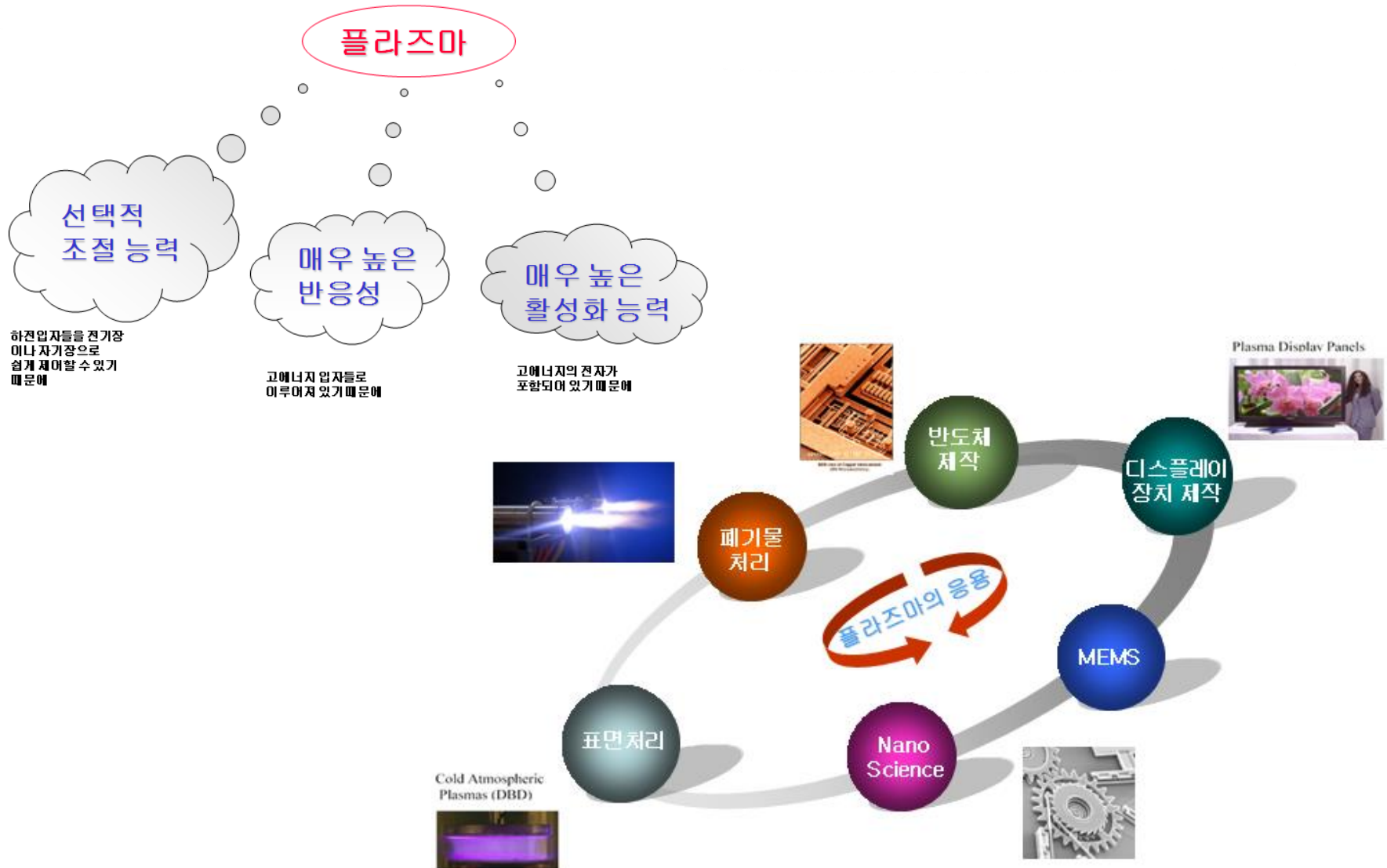




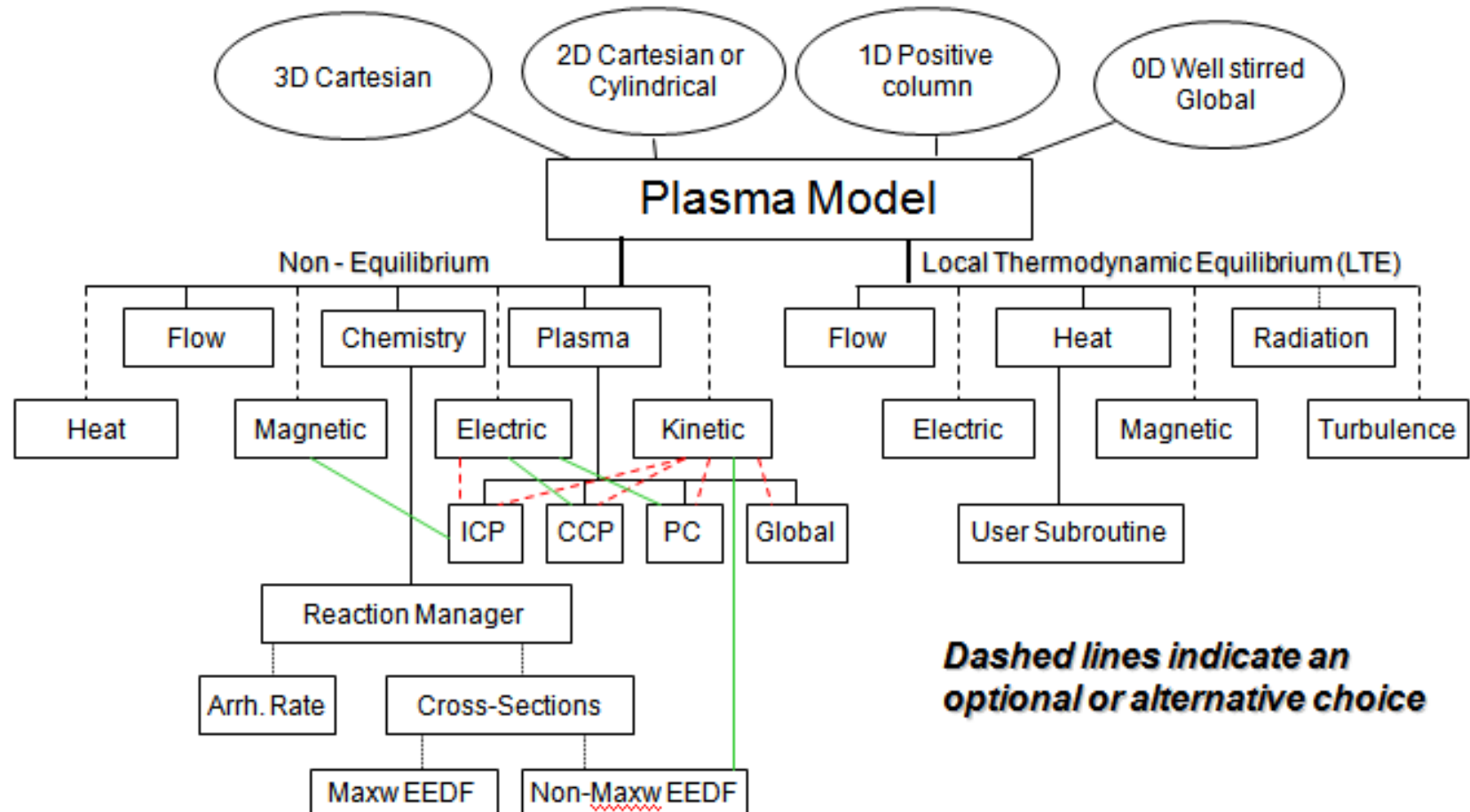
- Applications(Gas & surface reaction)



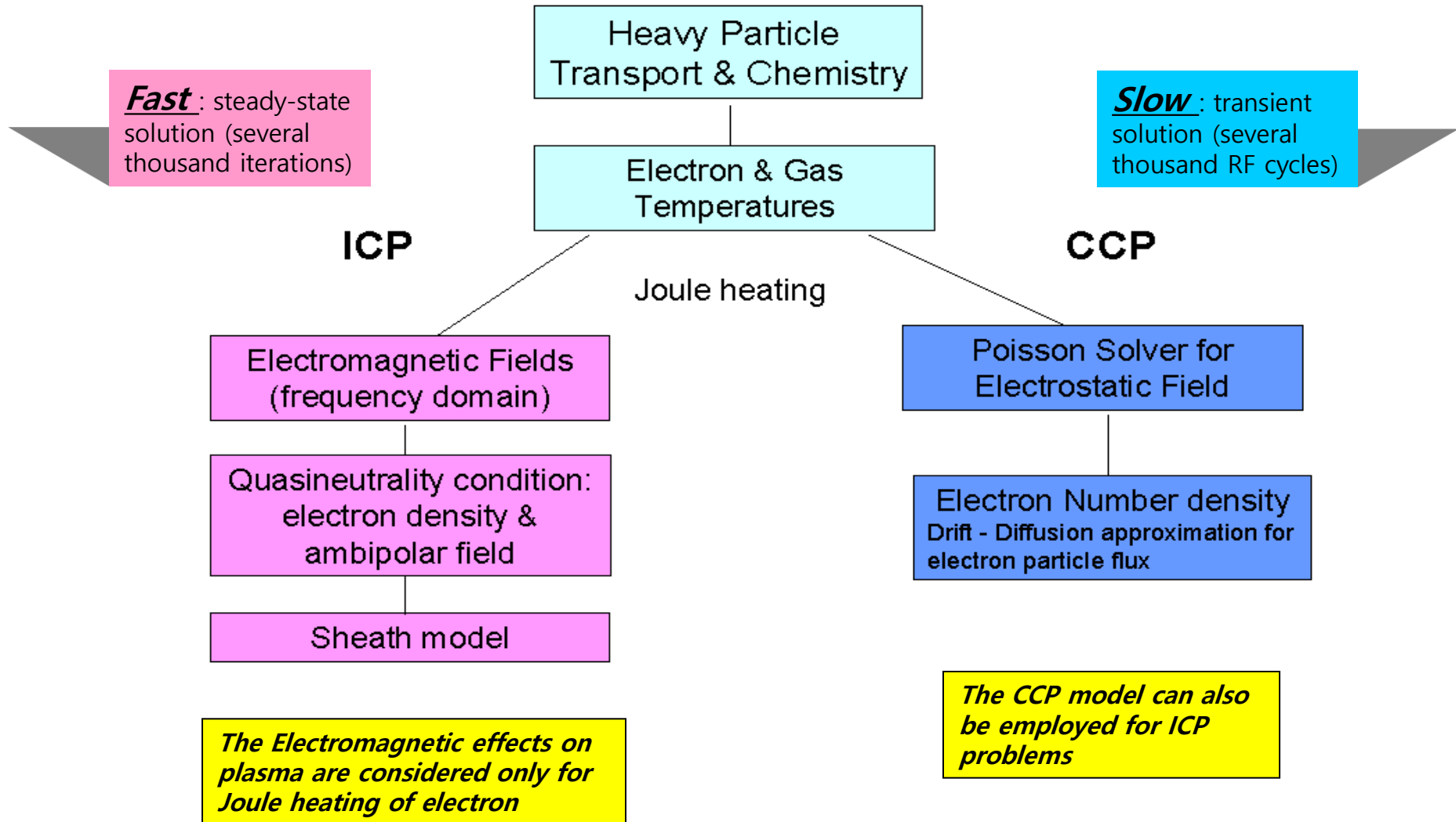
- Plasma Applications



- Plasma Simulation Logic.

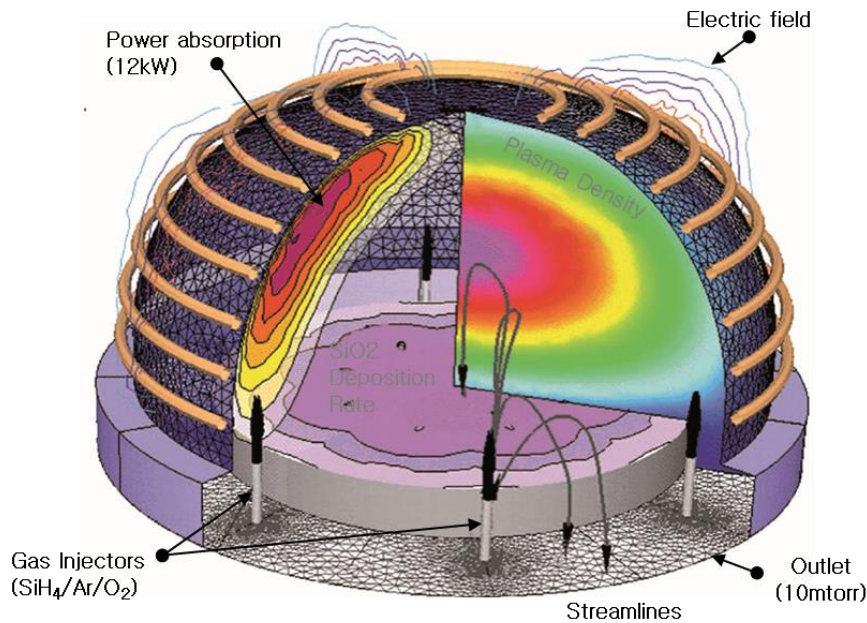


## CFD-ACE+ Plasma Model



## Inductively Coupled Plasma (ICP)

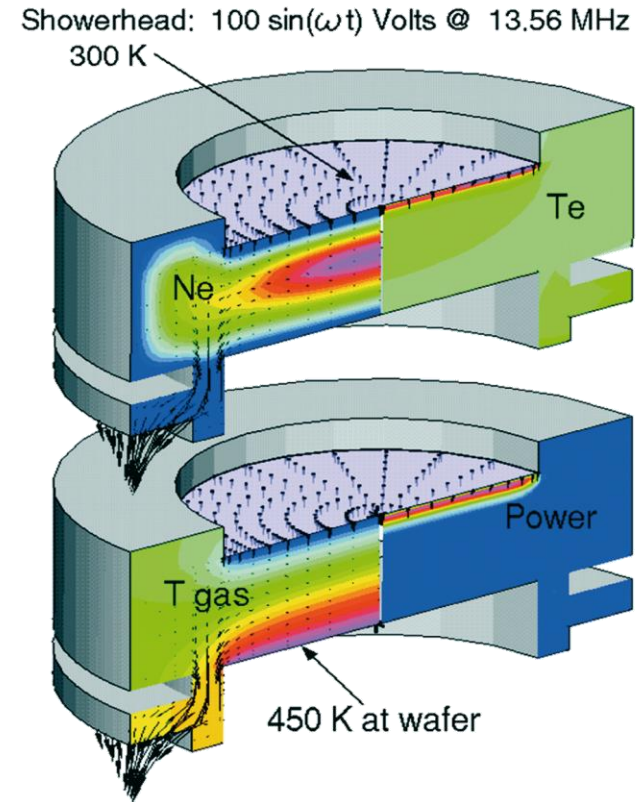
CFD-ACE+ – Simulation of SiO<sub>2</sub> deposition in an Inductively Coupled Plasma (ICP) reactor



*Inductively Coupled Plasma(ICP) Reactor*

## Capacitively Coupled Plasma (CCP)

CFD-ACE+ 3D – Simulation of Capacitively Coupled Plasma (CCP) for Oxygen at 400 millitorr



*Capacitively Coupled Plasma(CCP) Reactor*